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## **BIB DATA SHEET**

## **CONFIRMATION NO. 9573**

### RIVE #### APPLICANTS   Minoru Sugawara, Kanagawa, JAPAN;  ****CONTINUING DATA ****  ***This application is a 371 of PCT/JP03/08377 07/01/2003  ***FOREIGN APPLICATIONS ***  JAPAN 2002-200777 07/10/2002  ***IF REQUIRED, FOREIGN FILING LICENSE GRANTED ***  Foreign Priority dalmed	Minoru Sugaw CONTINUING DA This applicatio FOREIGN APPLI JAPAN 2002- JAPAN 2002-
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3S USC 119(a-d) conditions met \( \overline{\overline{\text{V}}} \) Yes \( \overline{\text{INO}} \) No \( \overline{\text{Verified and}} \) Alchowledged \( \overline{\text{INS}} \) (PASHID A ALAW \( \overline{\text{Install}} \) (PASHID A ALAW \( \overline{\text{Install}} \) (PASHID A ALAW) \( \overline{\text{Install}} \) (PASHID A ALAW) \( \overline{\text{Install}} \) (PASHID A ALAW) (PASHID A A	IF REQUIRED, F
Acknowledged Examiner's Signature Initials JAPAN 48 20 3	USC 119(a-d) conditions
ADDRESS	ADDRESS
RADER FISHMAN & GRAUER PLLC LION BUILDING 1233 20TH STREET N.W., SUITE 501 WASHINGTON, DC 20036 UNITED STATES	LION BUILDIN 1233 20TH S WASHINGTO
TITLE	TITLE
Phase shift mask fabrication method thereof and fabrication method of semiconductor apparatus	Phase shift m
☐ All Fees	
☐ 1.16 Fees (Filing)	
FILING FEE RECEIVED No. to charge/credit DEPOSIT ACCOUNT    The control of the co	ILING FEE
1030 No for following:	
☐ Other	
☐ Credit	